Summary of previous slides :

We now know how most particles (i.e all particles that live long enough to reach a detector; e,u,p, π ,k,n, γ , neutrinos,etc) react with matter.

We now know how to identify particles to some extend, how to measure E and p, v, and how to measure lifetimes using secondary vertices, etc Lecture set 2 : but we skipped one essential step in the process

How are reactions of the various particles with detectors turned into electrical signals. We would like to extract position and energy information channel by channel from our detectors.

Three effects are usually used :

1 Ionisation

2 Scintillation

3 Semi Conductors

and these are used in either for tracking, energy measurements, photon detectors for Cherenkov or TRT, etc

4 Finally we will have a quick look at how electrical signals are amplified in FE electronics

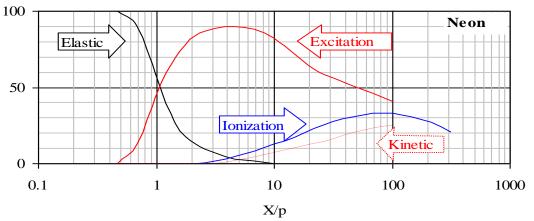
and from then on it is all online (trigger, DAQ) and offline treatment and analysis

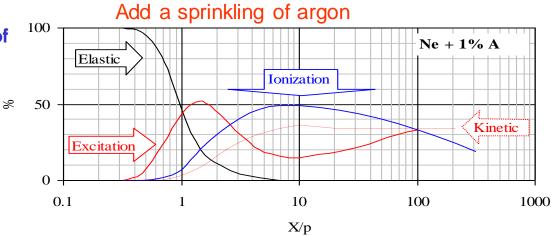
From CERN-CLAF, O.Ullaland

Approximate computed curves showing the percentage of electron energy going to various actions at a given X/p (V/cm/mmHg)

Elastic: loss to elastic impact Excitation: excitation of electron levels, leading to light emission and metastable states

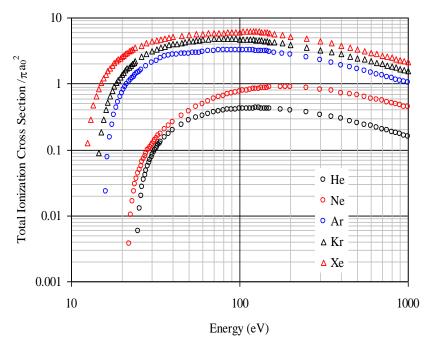
Ionization: ionization by direct impact Kinetic: average kinetic energy divided by their "temperature" Vibration: energy going to excitation of vibrational levels



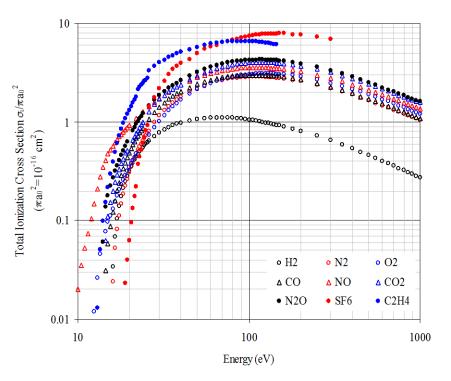


L. B. Loeb, Basic Processes of Gaseous Electronics

Experimental results. Rare gases.





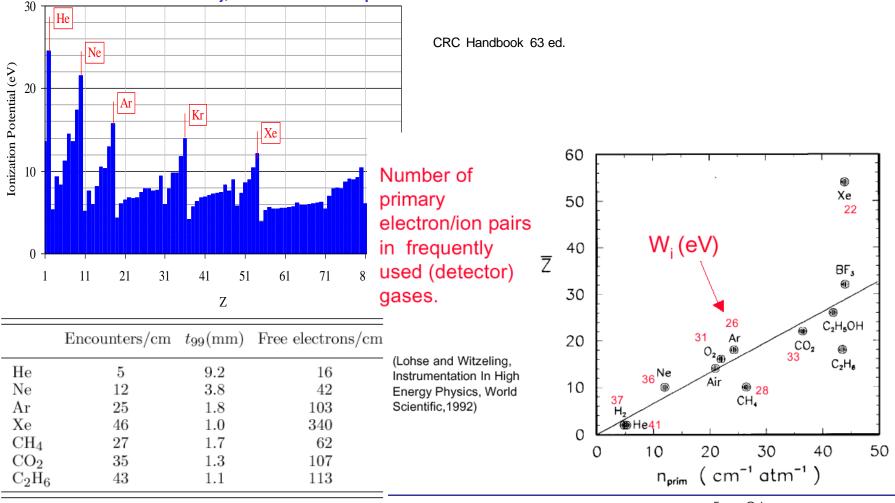


D. Rapp et al., Journal of Chemical Physics, 43, 5 (1965) 1464

Fig 1. Ionisation potiential. The work required to remove a given electron from its orbit and place it at rest at an infinite distance.

Fig 2. Note that limited number of primary electrons/ions.

Fig 3 (table). Taking into account that some of the primary electrons will ionise further (factor 3-4 increase); nevertheless keep in mind that electronics noise can be 300-500 ENC.



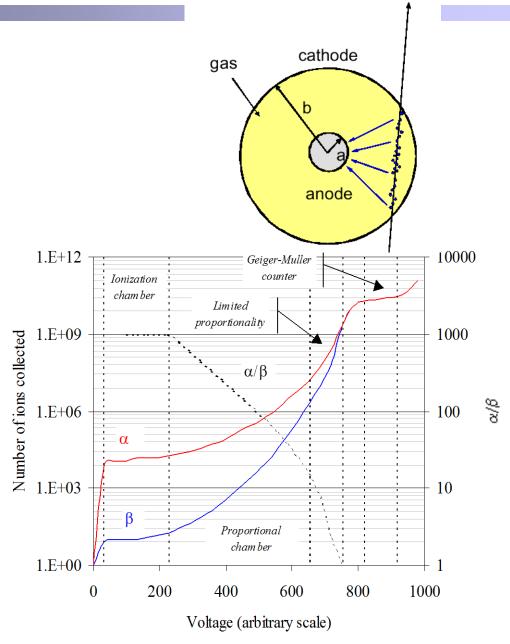
The different regions :

Recombination before collection.

lonisation chamber; collect all primary charge. Flat area.

Proportional counter (gain to 10⁶); secondary avalanches need to be quenched. Limited proportionality (secondary avalanches distorts field, more quenching needed).

Geiger Muller mode, avalanches all over wire, strong photoemission, breakdown avoided by cutting HV.



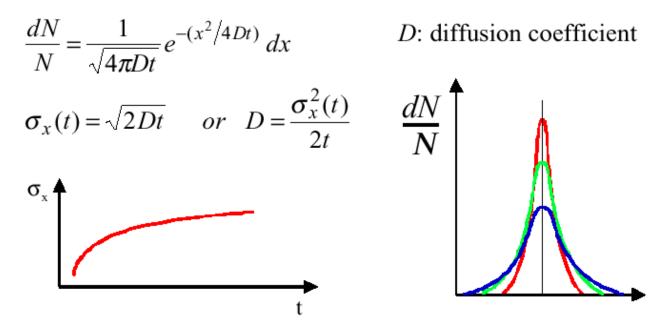
From C.Joram

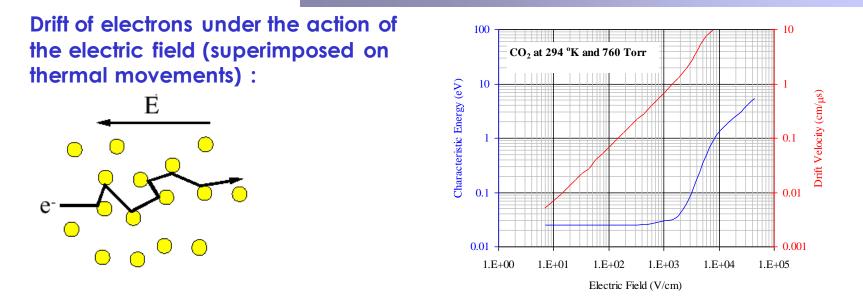
No external fields:

Electrons and ions will lose their energy due to collisions with the gas atoms \rightarrow thermalization

$$\varepsilon = \frac{3}{2}kT \approx 40 \text{ meV}$$

Undergoing multiple collisions, an originally localized ensemble of charges will diffuse





The drift velocity of the positive ions under the action of the electric field is linear with the reduced electric field (E/pressure) up to very high fields.

```
v <sup>+ions</sup> = \mu^{+ions} E where \mu^+ \propto 1/p and diffusion D^{+ions} \propto \mu^{+ions} T
```

```
\frac{v_{electron}}{v_{ion}} \approx 10^3
```

in CO_2 with $E=10^4$ V/cm

The amplification process :

From CERN-CLAF, O.Ullaland

Let a^{-1} be the mean free path (also called the first Townsend coefficient) between each ionization, in other words dn = nadx.

The gas amplification is then given by :

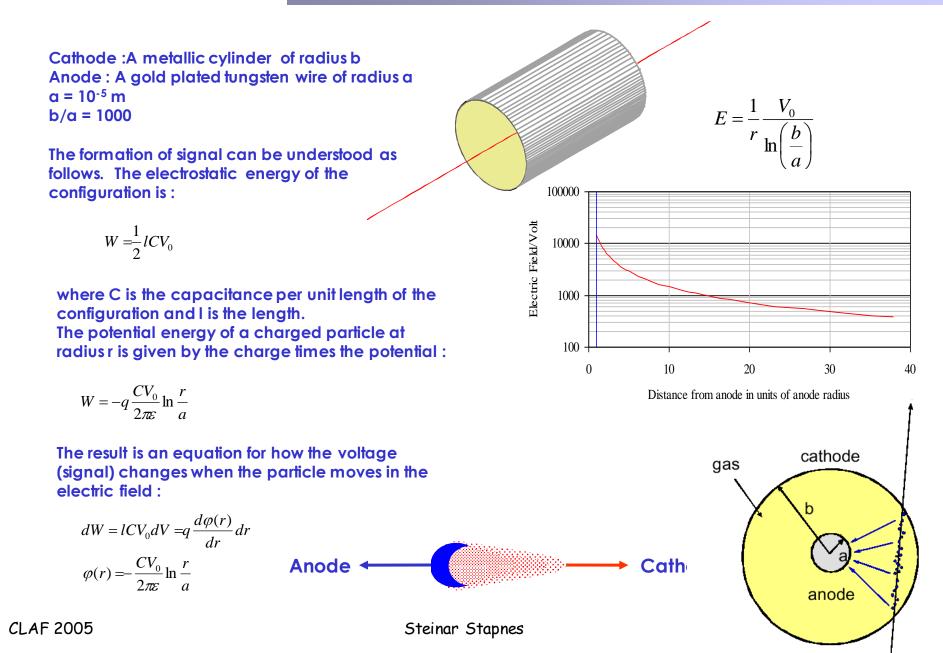
$$M = e^{\int_{x_1}^x \alpha(x) dx}$$

Korff's approximation (model) $\frac{\alpha}{n} =$

$$\frac{\alpha}{p} = Ae^{-Bp/E}$$

where A and B are gas dependent constants and p is the pressure.

			A	В
_	_		(Torr/cm)	(V Torr/cm)
$Bpr_0 \ln$	R	Не	3	34
	r_0	Ne	4	100
$M = \exp \left \frac{A}{V_0} \frac{V_0}{V_0} e^{-\frac{V_0}{V_0}} \right $		Ar	14	180
$M = \exp\left \frac{\frac{A}{B}}{\ln\frac{R}{2}}e^{-\frac{V_0}{V_0}}\right $		Xe	26	350
$\int \ln \frac{1}{r_0}$		CO2	20	466
1.E+06 1.E+05 1.E+04 1.E+03 1.E+02 1000	1500 Anode Voltage (V)	2000	for a gas mixtu Ar/CO ₂ : 80/20	



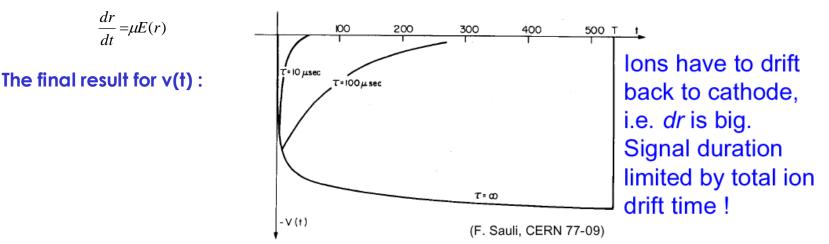
Signal induced by (mainly) the positive ions created near the anode. Assume that all charges are created within a distance λ from the anode. λ is of the order of a few 10's of $\mu m \rightarrow v_{electron} = v_{ion} / 100$ which can be seen from the equations below setting in the correct values for a and b :

$$v_{electron} = -\frac{Q}{lCV_0} \int_{a}^{a+\lambda} \frac{dV}{dr} dr = -\frac{Q}{2\pi\varepsilon l} \ln \frac{a+\lambda}{a}$$
$$v_{ion} = +\frac{Q}{lCV_0} \int_{a+\lambda}^{b} \frac{dV}{dr} dr = -\frac{Q}{2\pi\varepsilon l} \ln \frac{b}{a+\lambda}$$

Assuming a=0 and all the signal comes from the ions we can write:

$$v(t) = +\frac{Q}{lCV_0} \int_{r(0)}^{r(t)} \frac{dV}{dr} dr = -\frac{Q}{2\pi\epsilon l} \ln \frac{r(t)}{a}$$

r(t) can be taken from :

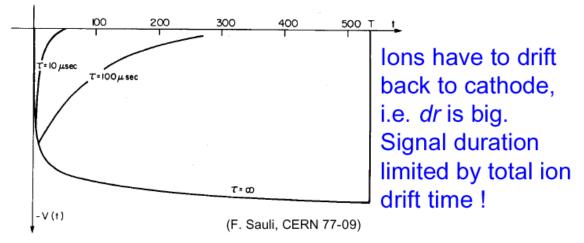


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Need electronic signal differentiation to limit dead time.

In modern fast ionisation detectors the electrons are used (faster) as well as the beginning of the ion signal.

For example if we use 5% of the signal with a gain 10⁴ we still have a healthy signal compared to the noise – and we can operate mostly with the fast part of the signal (electrons) and differentiate away the tails



Need electronic signal differentiation to limit dead time.

With these tools, we can now make :

Straw Tube

Multiwire Proportional Chambers

Drift Chambers

Time Projection Chambers

Thin Gap Chambers

Jet Chambers

etc

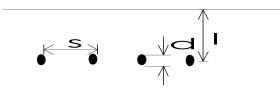
Still possible to calculate by hand (leave as exercise for you) :

$$V_{s}(z) \underset{d \to 0}{\approx} \frac{2\pi l}{s} - \ln \left\{ 4\sin^{2} \left(\frac{\pi x}{s}\right) + 4\sinh^{2} \left(\frac{\pi y}{s}\right) \right\}$$

$$Q = \frac{V_0}{\frac{2\pi l}{s} - 2\ln\frac{\pi d}{s}} \qquad \text{and} \qquad E_0 = \frac{sV_0}{\frac{\pi d}{2} \left[l - \frac{s}{\pi} \ln\frac{\pi d}{s} \right]}$$

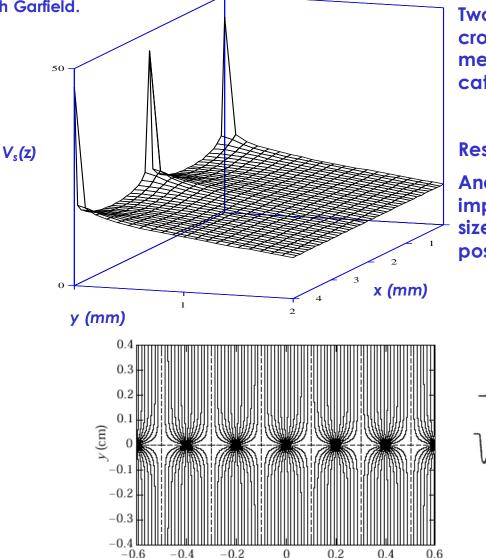
From CERN-CLAF, O.Ullaland

Classic Multi-Wire Proportional Chamber (MWPC) Typical parameters : I : 5 mm s : 2 - 4 mm d : 20 mm



Advanced calculations of electric field, drift, diffusion and signal formation can be done with Garfield.

Ionisation Detectors

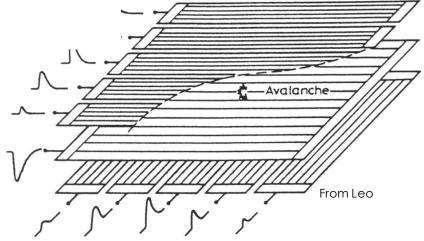


x (cm)

Two dimensional readout can be obtained by; crossed wires, charge division with resistive wires, measurement of timing differences or segmented cathode planes with analogue readout

Resolution given by (binary readout): $\sigma = d / \sqrt{12}$

Analogue readout and charge sharing can improve this significantly when the left/right signal size provide more information about the hit position.

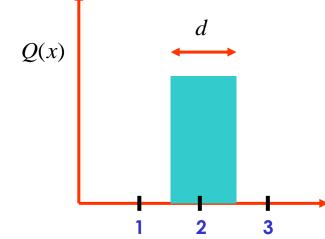


$$y = \frac{\sum (Q_i - b) y_i}{\sum (Q_i - b)} ,$$

Steinar Juppes

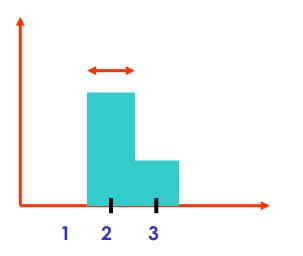
Resolution

Charge on a single wire/strip is the worst possible situation for the resolution:



$$\sigma^{2}(x) = \int Q(x) (x - \bar{x})^{2} dx = d^{2}/12$$

where Q(x) is charge readout in position x (in this case a box with w idth equal to the pitch)



With analogue readout and charge sharing we improve the information content significantly – on the left we know that the hit was between the second and third readout electrode and closest to the 2nd, so we can make a probability function which is much more narrow (some times pitch/10).

Another way of saying it: For every point between wire/strip 2 and 3 there is a unique value of : $(Q_2-Q_3)/(Q_2+Q_3)$, so by measuring this quantity we can reconstruct the position.

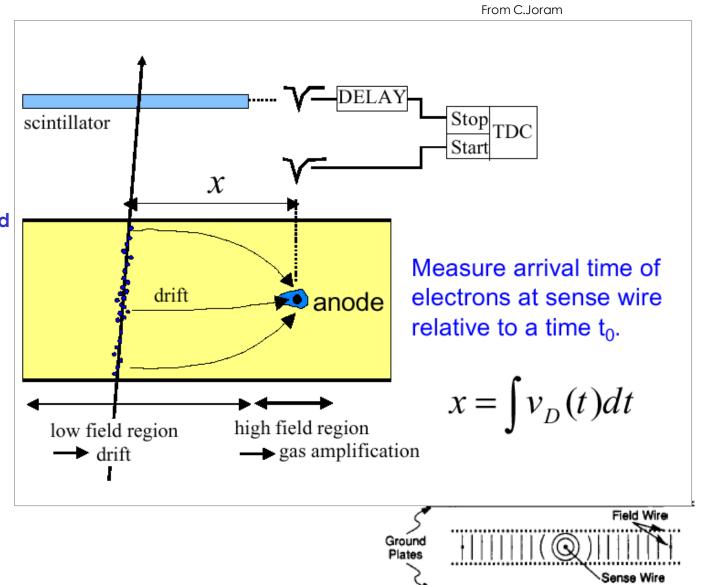


Reduced numbers of readout channels

Distance between wires typically 5-10cm giving around 1-2 µs drift-time

Resolution of $50-100\mu m$ achieved limited by field uniformity and diffusion

More problems with occupancy



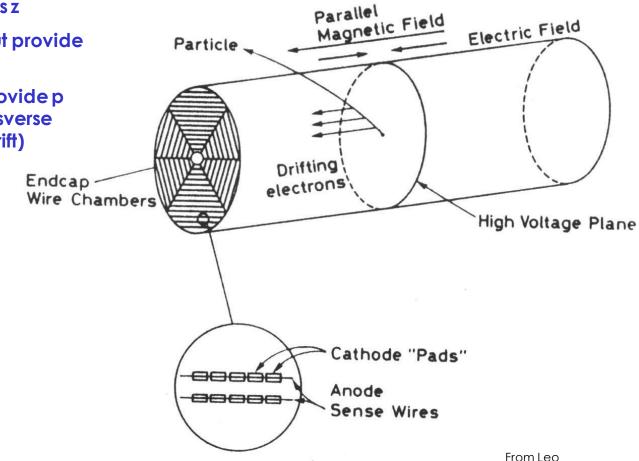
Time projection chamber :

Drift to endplace where x,y are measured

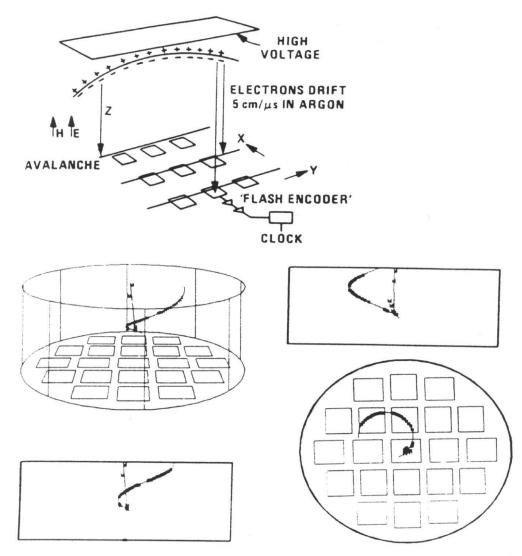
Drift-time provides z

Analogue readout provide dE/dx

Magnetic field provide p (and reduce transverse diffusion during drift)



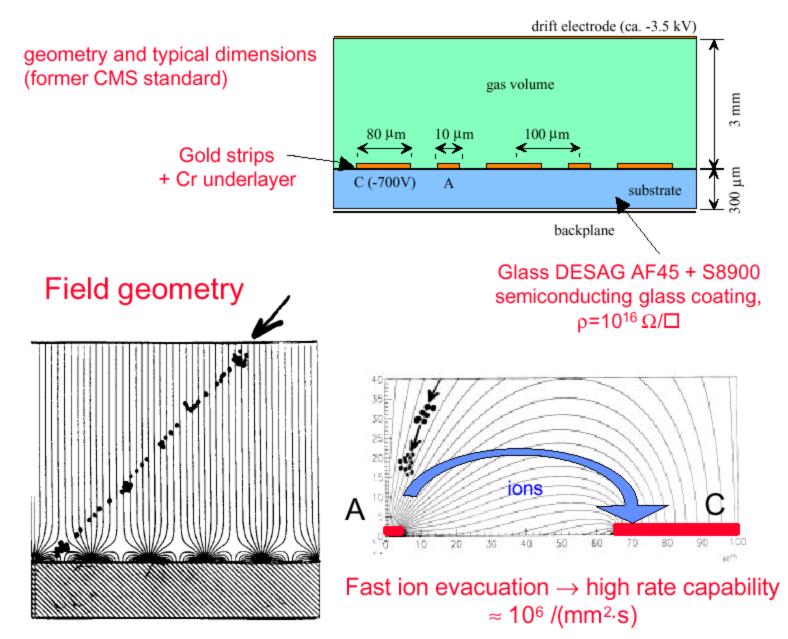
The Time Projection Chamber (TPC)



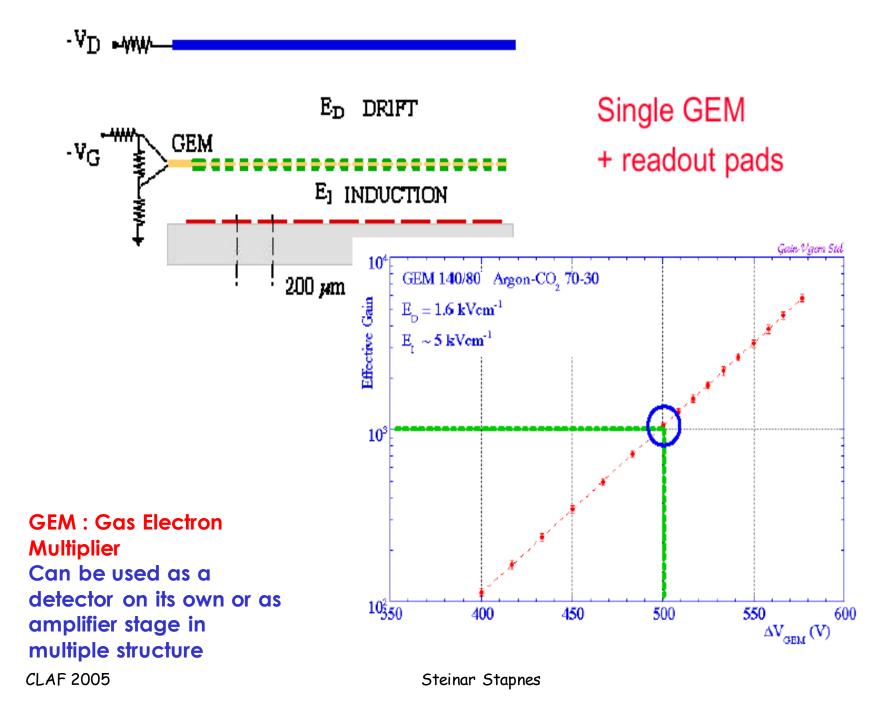
In recent years there has been several developments directed towards making gas detectors more suitable for high rate applications (inner detectors components for LHC). I will mention only two (C.Joram; CERN summer student lectures 2002) :

Microstrip gas chambers

(A. Oed, NIM A 263 (1988) 352)

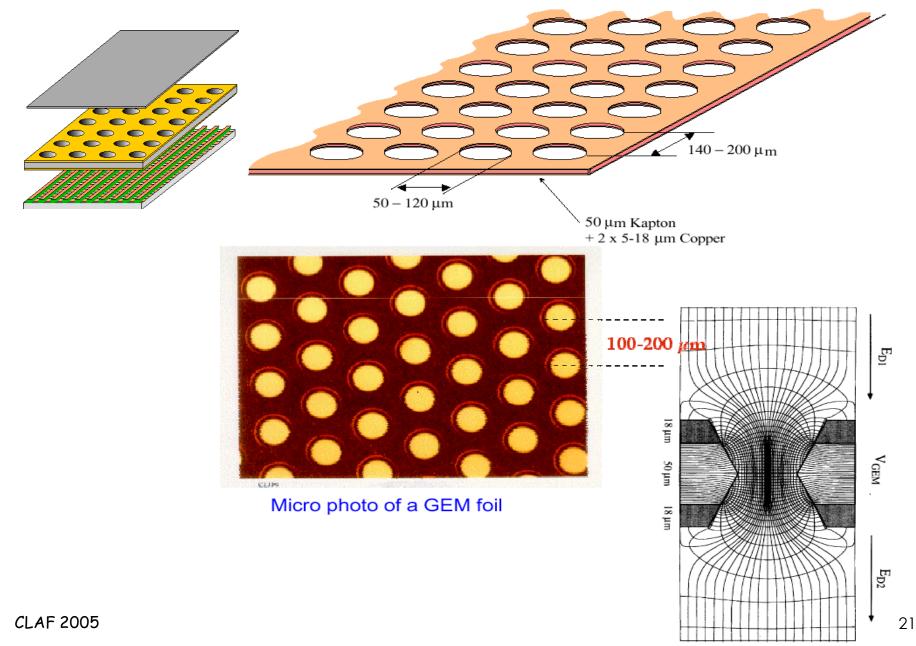


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GEM: The Gas Electron Multiplier

(R. Bouclier et al., NIM A 396 (1997) 50)



Scintillators

Scintillators are used in many connections :

• Calorimetry (relatively cheap and good energy resolution)

- •Tracking (fibres)
- Trigger counters
- •Time of flight
- Veto Counters

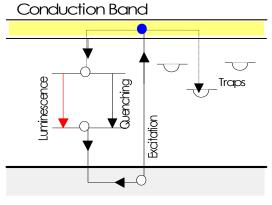
Will discuss mainly inorganic (often used in calorimeters due to high density and Z; slow but high light output and hence good resolution) and organic (faster but less light output)

Will discuss readout (wavelength shifters, photon detectors and new developments to increase granularity of the readout).

Scintillators

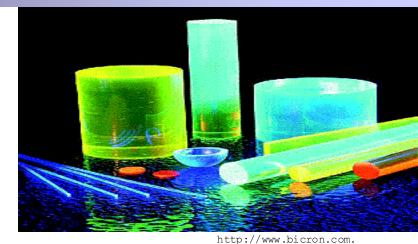
Inorganic Crystalline Scintillators The most common inorganic scintillator is sodium iodide activated with a trace amount of thallium [NaI(TI)],

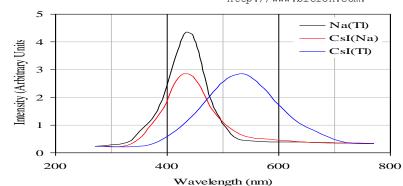
Energy bands in impurity activated crystal

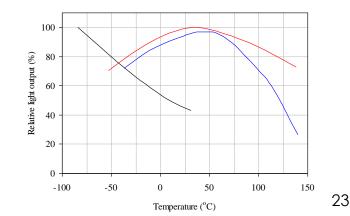


Valence Band

Strong dependence of the light output and the decay time with temperature.







Steinar Stapnes

Parameters for some common scintillator materials

Crystal (g	hog/cm ³)		$r_{ m Molière}$ (cm) (1		λ_I (cm)	$\frac{\tau_{ m decay}}{ m (ns)}$	λ_{\max}	n_D	Rel. output [*]	Hygro?
NaI(Tl)	3.67	2.59	4.5	4.8	41.4	250	410	1.85	1.00	very
BGO	7.13	1.12	2.4	9.2	22.0	300	410	2.20	0.15	no
BaF_2	4.89	2.05	3.4	6.6	29.9	0.7^{f}	220^{f}	1.56	0.05^{f}	slightly
						620^{s}	310^{s}		0.20^{s}	
CsI(Tl)	4.53	1.85	3.8	5.6	36.5	1000	565	1.80	0.40	some
CsI(pure)	4.53	1.85	3.8	5.6	36.5	$10, 36^{f}$	305^{f}	1.80	0.10^{f}	some
						$36^{f}, 620^{s}$	$\sim 480^s$		0.20^{s}	
$PbWO_4$	8.28	0.89	2.2	13.0	22.4	5 - 15	420440^\dagger	2.3	0.01	no
${\rm CeF_3}$	6.16	1.68	2.6	7.9	25.9	10 - 30	310 - 340	1.68	0.10	no

Nal has a light output of typically 40000 photons per MeV; keep in mind that light collection, and the quantum efficiency of the photo detector will reduce the signal significantly.

The detector response is fairly linear (see Leo).

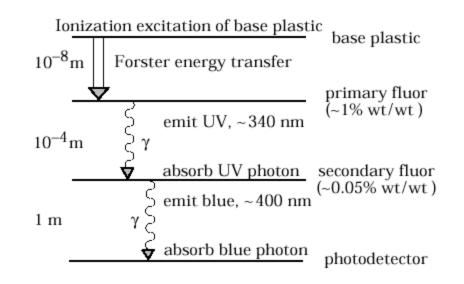
Scintillators

Organic Scintillators These are fast and with typical light output around half of Nal. Practical organic scintillators uses a solvents; typically organic solvents which release a few % of the exited molecules as photons (polystyrene in plastic for example, xylene in liquids) + large concentration of primary fluor which transfers to wavelengths where the scintillator is more transparent (Stokes shift) and changes the time constant

+ smaller concentration of secondary fluor for further adjustment

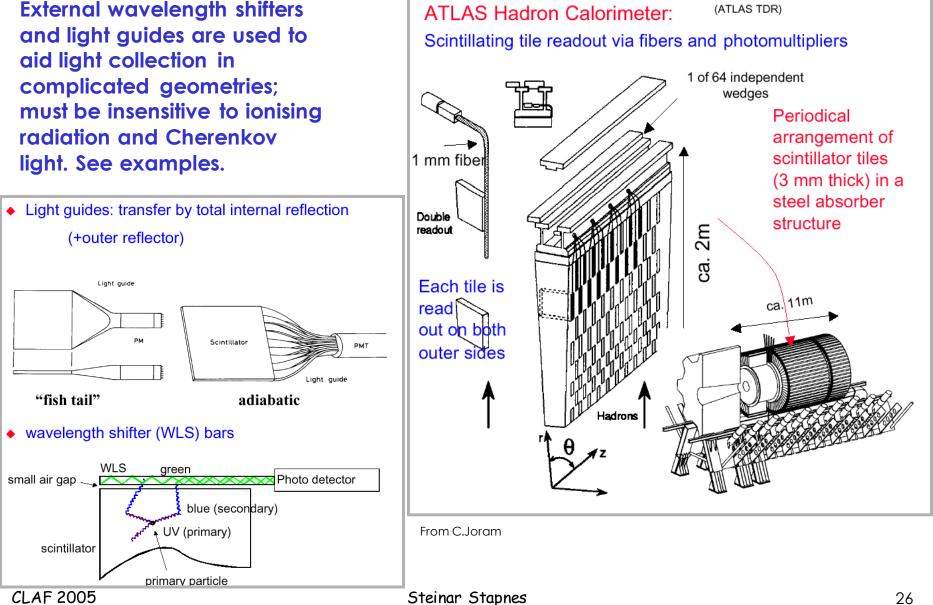
+

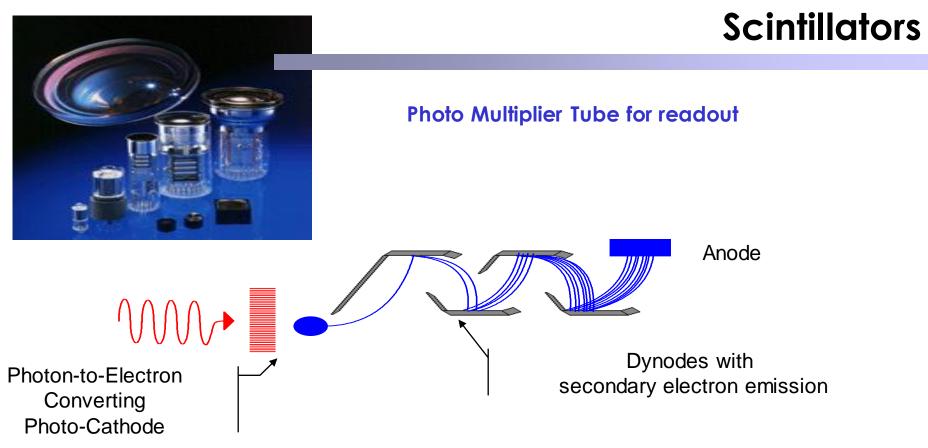
Generally the final light output has two time constants and the relative contributions from them depend on the energy deposition (particle type); this can be used for particle identification (pulse shape discrimination). This is for example used for neutron counting; the detectors are sensitive to proton recoils (contain hydrogen) from neutrons.



List of materials and solvents can be found in most textbooks

Scintillators

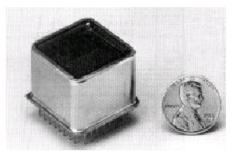




Multi Anode PM example: Hamamatsu R5900 series.

Typical gain $\approx 10^6$ Transient time spread ≈ 200 ps Limited space resolution

http://www.hamamatsu.com/



Up to 8x8 channels. Size: 28x28 mm². Active area 18x18 mm² (41%). Bialkali PC: Q.E. = 20% at λ_{max} = 400 nm. Gain $\approx 10^6$

Scintillators

From CERN-CLAF, O.Ullaland

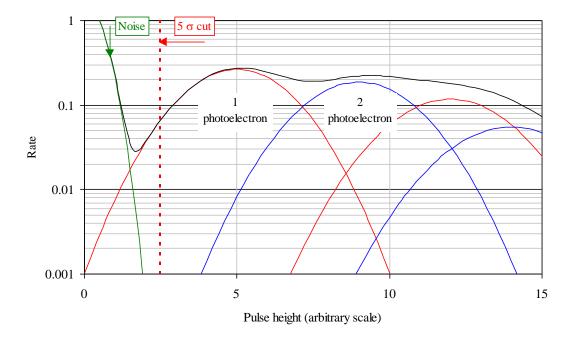
The energy resolution is determined mainly by the fluctuation of the number of secondary electrons emitted at each dynode.

Poisson distribution

$$P(r,\mu) = \frac{\mu^r e^{-\mu}}{r!}$$

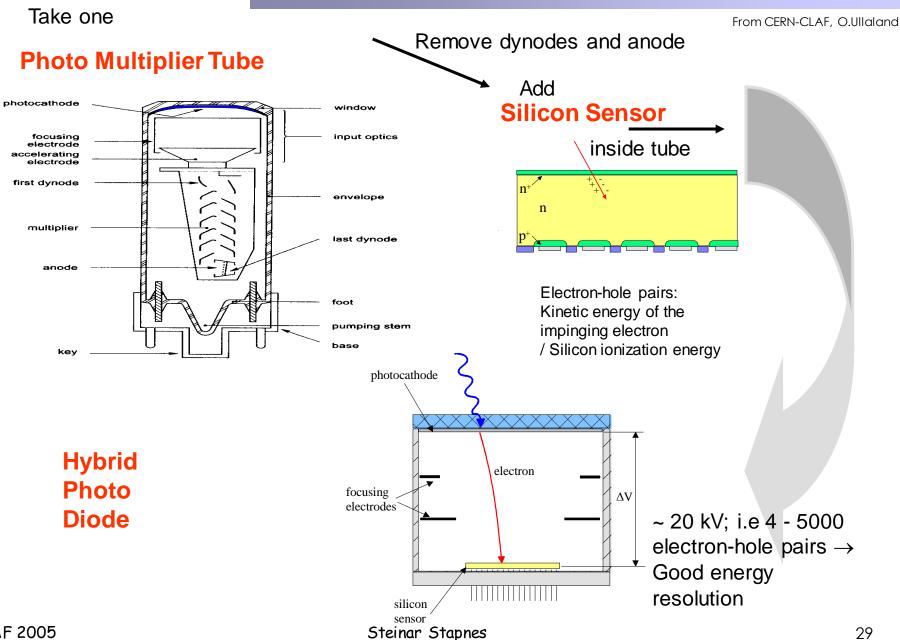
where m = mean number = the variance r = 1, 2, 3 ...

Fluctuations mainly induced at the first dynode where the number of primary electrons are small



Physical principles of Hybrid Photo Diodes

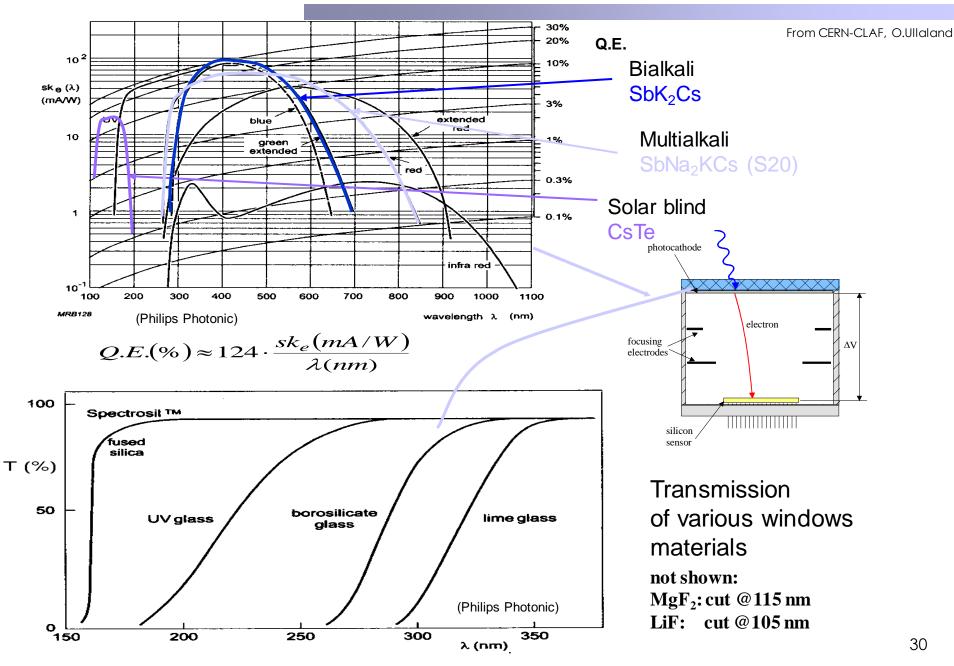
Scintillators



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Hybrid Photo Diode

Scintillators

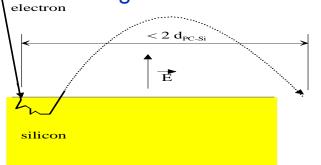


But...



From CERN-CLAF, O.Ullaland

- Electronic noise, typically of the order of $\geq 500 \text{ e}$ $\sigma_{total}^2 = \sigma_{int.}^2 + \sigma_{E_{loss}}^2 + \sigma_{elec.}^2 >> \sigma_{int.}^2$
 - Back scattering of electrons from Si surface

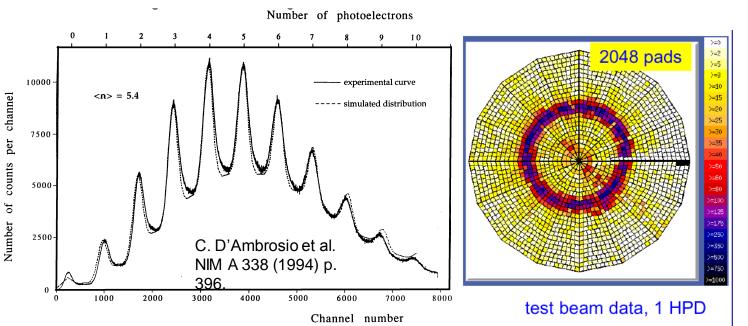


back scattering probability at E \approx 20 kV

 $\alpha_{Si} \approx 0.18$

20% of the electrons deposit only a fraction $o \le \varepsilon < 1$ of their initial energy in the Si sensor .

 \rightarrow continuous background (low energy side)



Solid state detectors have been used for energy measurements a long time (Si,Ge...). It takes a few eV to create an e/h pairs so the energy resolution is very good.

Nowadays silicon detectors are mostly used for tracking.

From C.Joram

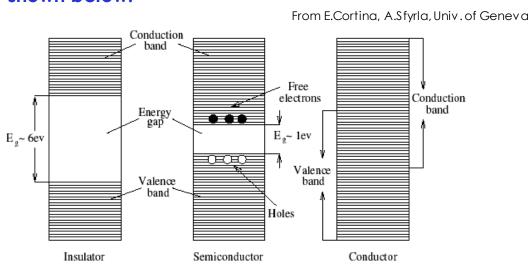
Some characteristic numbers for silicon

- d Band gap: E_g =1.12eV.
- $E(e^{-}-hole pair) = 3.6 eV$, ($\approx 30 eV$ for gas detectors).
- \blacklozenge High specific density (2.33 g/cm³) $\rightarrow \Delta \text{E/track}$ length for
 - M.I.P.'s.: 390 eV/ μ m \approx 108 e-h/ μ m (average)
- \checkmark High mobility: $\mu_e = 1450 \text{ cm}^2/\text{Vs}$, $\mu_h = 450 \text{ cm}^2/\text{Vs}$
- d Detector production by microelectronic techniques → small dimensions → fast charge collection (<10 ns).</p>
- Rigidity of silicon allows thin self supporting structures.

Typical thickness 300 μ m $\rightarrow \approx 3.2 \cdot 10^4$ e-h (average)

P But: No charge multiplication mechanism!

When isolated atoms are brought together to form a lattice, the discrete atomic states shift to form energy bands as shown below.



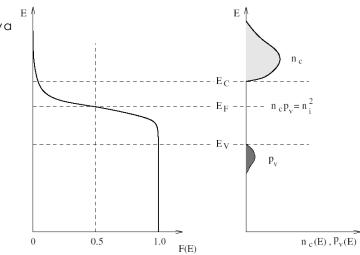


Figure 2: Occupation probability and carrier concentration for intrinsic semiconductors.

The number of states per volume and energy can be calculated – from this we can derive the number of electrons in the conduction band and holes in the valence band – per unit volume (as a function of temperature)

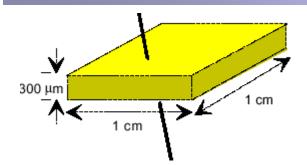
For basic semi-conduction physics see :

http://jas.eng.buffalo.edu/index.html

Text, illustrations, models and online diagrams, etc ...

$$P(W) \propto \exp\left[-\frac{W-W_F}{kT}\right]$$

W_F = Fermi Level = the Energy where P(W)=1/2



Intrinsic silicon will have electron density = hole density; 1.45 10^{10} cm⁻³ (from basic semiconductor theory).

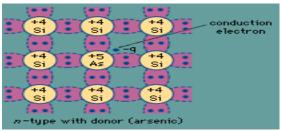
In the volume above this would correspond to 4.510⁸ free charge carriers; compared to around $3.2 \ 10^4$ produces by MIP (Bethe Bloch loss in 300um Si divided by 3.6 eV).

Need to decrease number of free carriers; use depletion zone (reduce temperature would also help but one would need to go to cryogenic temperatures)

Doping of semiconductors.

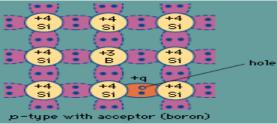
Semi-Conductors

N-Type



P-Type





The zone between the N and P type doping is free of charge carriers, forms an capasitor, have an electric field and is well suited as detector volume; need to increase by applying reverse biasing

P, As, Sb 5 electrons in the Mshell \rightarrow 1 electron with binding energy 10-50 meV

B, Al, Ga 3 electrons in the Mshell

 \rightarrow 1 electron missing

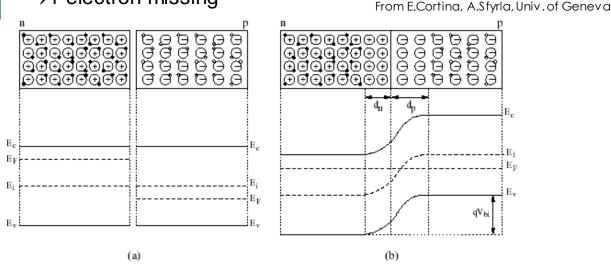
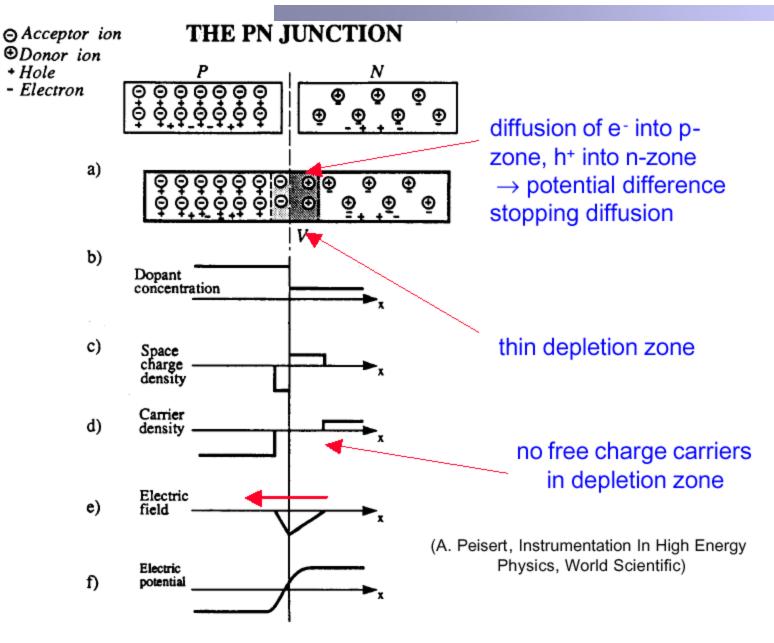


Figure 4: A p - n junction in thermal equilibrium, with its parts separated (a) and brought together (b) forming a potential barrier.

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One can quickly establish the most critical parameters for a silicon detector by looking at the p,n junction above :

Poisson's equation :

With charge density from $-x_{\rm p}$ to 0 and from 0 to $x_{\rm n}$ defined by :

 N_{D} and N_{A} are the doping concentrations (donor, acceptor).

The depletion zone is defined as :

By integrating one the E(x) can be determined, by integrating twice the following two important relations are found: $V \propto d^2$

$$C = \varepsilon \frac{A}{d} \propto V^{-1/2}$$

By increasing the voltage the depletion zone is expanded and C (capasitance) decreased – giving decreased electronics noise.

 $\frac{d^2 V}{dx^2} = -\frac{\rho(x)}{\varepsilon}$ $\rho(x) = \pm e N_{D/A}$

Semi-Conductors

 $N_D x_p = N_A x_n$

$$d = x_p + x_n$$

Signal formation in general terms

For ionisation detectors we used energy balance to look at how a voltage signal was created due to charge drifting in the device. More general we have to use the Shockley-Ramo theorem for induced charge:

$$i = q \vec{v} \cdot \vec{E}_0$$

or

 $Q = q\Delta \varphi_0$

where \vec{E}_0 is the weighting field and $\Delta \varphi_0$ the potential difference from the beginning to the end of the path. The weighting potential is found by solving Laplace equation with some artificial boundary conditions (for the electrode under study (= unity) and for all other electrodes (= 0)).

The main message is that the signal is induced by the motion of charge after incident radiation (not when the charge reach the electrodes).

References:

Appendix D in ref (7) or chapter 5 of Particle Detection with Drift Chambers, W.Blum and L.Rolandi, Springer Verlag, ISBN 3-540-58322-X

For ionisation chambers it can be used to study not only the signal on the primary anode but also for the neighbours, or the cathode strips (if these are read out). For silicon detectors to study charge sharing between strips or pixels.

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Let us have look at the signal formation using the same simple model of the detector as two parallel electrodes separated by d.

A electric charge q moving a distance dx will induce a signal dQ on the readout electrode :

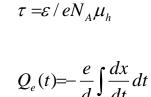
dQ d = q dx

As in the case of the proportional chamber we use :

giving

where

The time dependent signal is then :

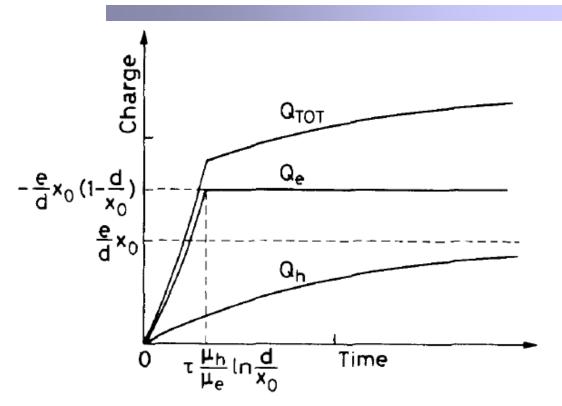


 $x(t) = x_0 \exp(\frac{\mu_e t}{\mu_h \tau})$

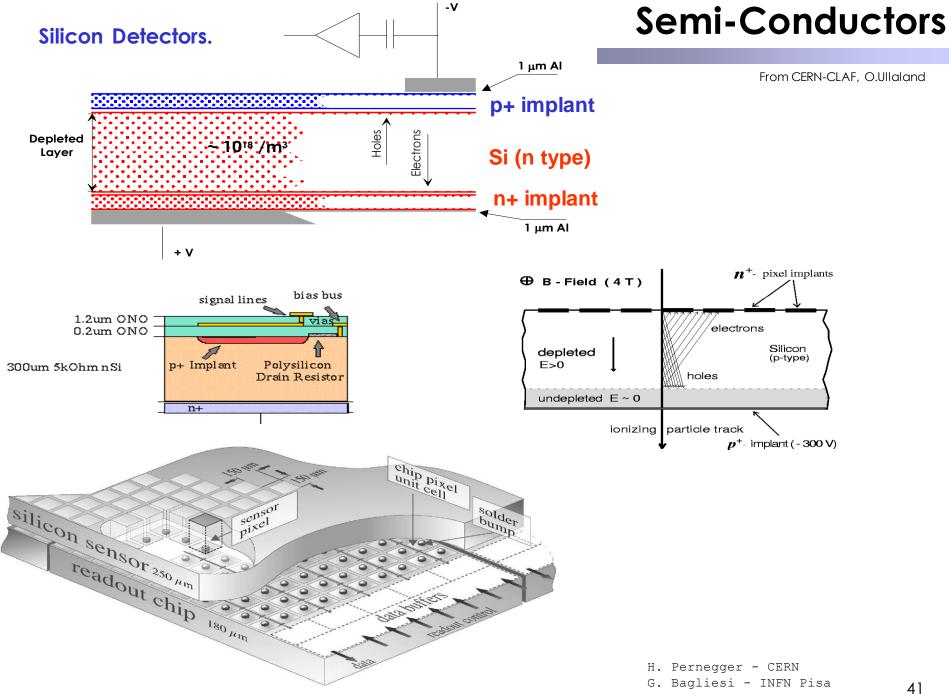
 $\frac{dx}{dt} = \mu E(x)$

The final result showing (when entering real numbers and using a more complete model) timescales of 10/25 ns for electron/hole collection :

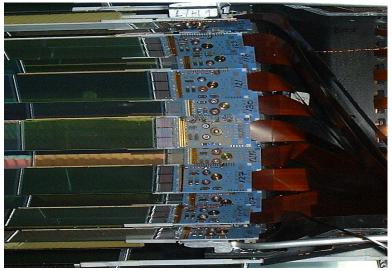
However, there are many caveats: In reality one as to start from the real e/h distribution from a particle. Use a real description of E(x) taking into account strips and over-depletion. Traps and changes in mobility can also come in, etc



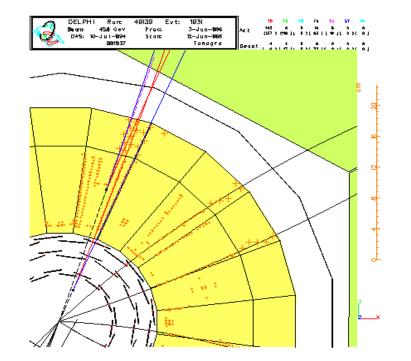
From Leo



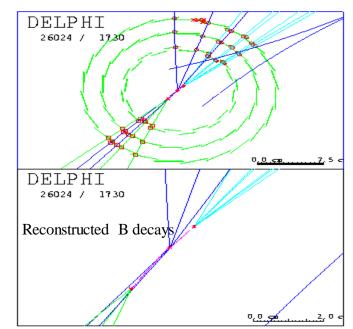
The DELPHI Vertex Detector



K0 and Lambda reconstruction



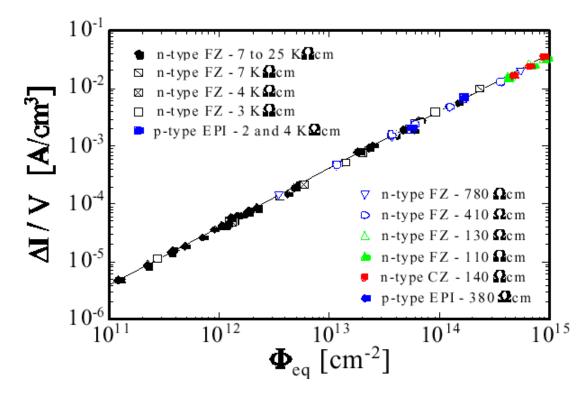
From CERN-CLAF, O.Ullaland



At the moment silicon detectors are used close to the interaction region is most collider experiments and are exposed to severe radiation conditions (damage).

The damage depend on fluence obviously as well particle type (π,γ,e,n,etc) and energy spectrum and influences both sensors and electronics. The effects are due to bulk damage (lattice changes) and surface effects (trapped charges). Three main consequences seen for silicon detectors (plots from C.Joram):

(1) Increase of leakage current with consequences for cooling and electronics



(2) Change in depletion voltage, high at end of lifetime of detector; combined with increased leakage current this leads to cooling problems again

(3) Decrease of charge collection efficiency (less and slower signal)

 $=10^{3}$ 5000 U_{dep} [V] (d = 300 µm) 1000 cn^{-j} 10^{2} **≂** 600 V 500 type inversion "Donor 100 removal" 10^{1} $10^{14} \, \mathrm{cm}^{-2}$ 50 "Acceptor 10 creation" Neff 10^{0} 5 n - type "p - type" 1 10-1 10^{3} $10^{\overline{2}}$ 10^{0} 10^{-1} 10^{1} Φ_{eq} [10^{12} cm⁻²] [Data from R. Wunstorf 92] p+ Charge trapping n in defects n⁺

· Defect engineering.

2

ROSE / RD48 http://cern.ch/rd48

Semi-Conductors

More fun: some of the ongoing R&D (C.Joram)

formation. Example Oxygen. Diffusion Float Zone Oxygenated (DOFZ) silicon used in ATLAS pixel detector. Gain a factor 3.

Introduce specific impurities in silicon, to influence defect

Cool detectors to cryogenic temperatures http://cern.ch/rd39
 (optimum around 130 k)

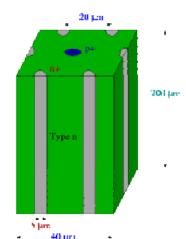
"zero" leakage current, good charge collection (70%) for heavily irradiated detectors ($1 \cdot 10^{15} \text{ n/cm}^2$). "Lazarus effect"

New materials

RD42 http://cern.ch/rd42

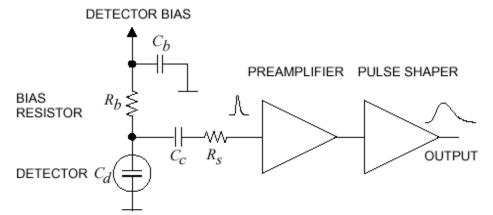
Diamond. Grown by Chemical Vapor Deposition. Very large bandgap (≈ 6 eV). No doping and depletion required! Material is still rather expensive. Still more R&D needed.

 New detector concepts
 "3D detectors" → "horizontal" biasing faster charge collection but difficult fabrication process



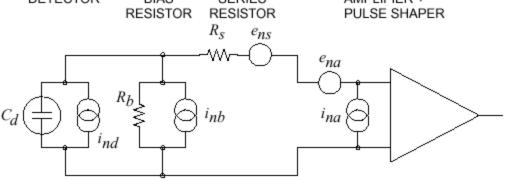
Front End electronics

Most detectors rely critically on low noise electronics. A typical Front End is shown below :



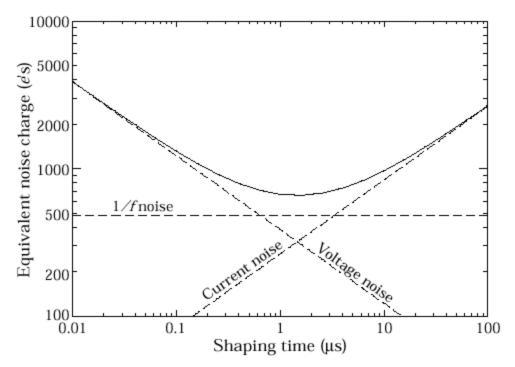
where the detector is represented by the capasitance C_d , bias voltage is applied through R_b , and the signal is coupled to the amplifier though a capasitance C_c . The resistance R_s represent all the resistances in the input path. The preamplifier provides gain and feed a shaper which takes care of the frequency response and limits the duration of the signal.

The equivalent circuit for noise analysis includes both current and voltage noise sources labelled i_n and e_n respectively. Two important noise sources are the detector leakage current (fluctuating-some times called shot noise) and the electronic noise of the amplifier, both unavoidable and therefore important to control and reduce. The diagram below show the noise sources and their representation in the noise analysis: DETECTOR BIAS SERIES AMPLIFIER +



Front End electronics

While shot noise and thermal noise has a white frequency spectrum (dP_n/df constant), trapping/detrapping in various components will introduce an 1/f noise. Since the detectors usually turn the signal into charge one can express the noise as equivalent noise charge, which is equivalent of the detector signal that yields signal-to-noise ratio of one. For the situation we have described there is an optimal shaping time as shown below :



Increasing the detector capasitance will increase the voltage noise and shift the noise minimum to longer shaping times.

Front End electronics

For quick estimates, one can use the following equation, which assumes an FET amplifier (negligible i_{na}) and a simple CR-RC shaper with time constants τ (equal to the peaking time):

$$(Q_n/e)^2 = 12 \left[\frac{1}{\mathrm{nA} \cdot \mathrm{ns}} \right] I_d \tau + 6 \times 10^5 \left[\frac{\mathrm{k\Omega}}{\mathrm{ns}} \right] \frac{\tau}{R_b} + 3.6 \times 10^4 \left[\frac{\mathrm{ns}}{(\mathrm{pF})^2 (\mathrm{nV})^2 / \mathrm{Hz}} \right] e_n^2 \frac{C^2}{\tau} .$$
(27.26)

which shows that the critical parameters are detector capasitance, the shaping time τ , the resistances in the input circuit, and the amplifier noise parameters. The latter depends mostly on the input device (transistor) which has to optimised for the load and use. One additional critical parameter is the current drawn which makes an important contribution to the power consumption of the electronics.

Practical noise levels vary between 10²-10³ ENC for silicon detectors to 10⁴ for high capasitance LAr calorimeters (10⁴ corresponds to around 1.6fC).

Instrumentation

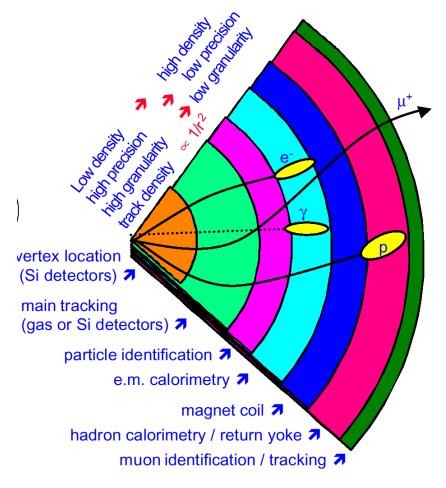
We now know how most particles (i.e all particles that live long enough to reach a detector; e,u,p, π ,k,n, γ , neutrinos,etc) react with matter.

We now know how to identify particles to some extend, how to measure E and p, v, and how to measure lifetimes using secondary vertices, etc

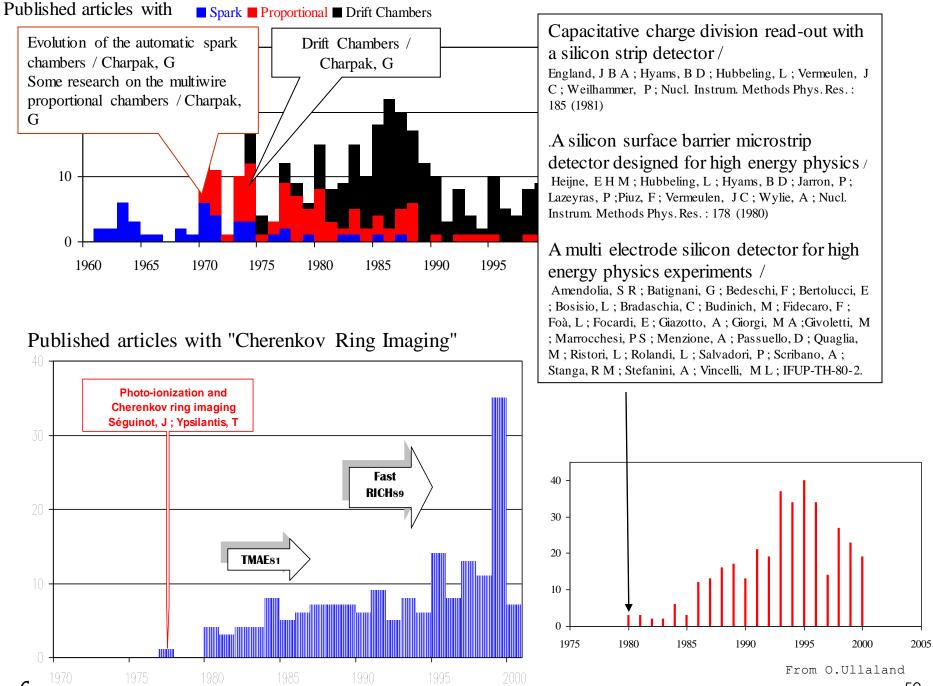
Essential three detector types are used :

- 1 Ionisation detectors
- **2** Scintillators
- **3 Semi Conductors**

4 Finally we have looked briefly at how electrical signals are treated in FE electronics



The detector-types mentioned are either for tracking, energy measurement, photon detectors for Cherenkov or TRT, etc in various configurations.



Improved detectors will certainly be needed. Linear colliders, TESLA and LHC upgrades will drive this development and things are already happening.

I would identify some main areas of research :

- Radiation hardness will remain a headache. Both for trackers and calorimeters, detector elements, materials and electronics.
- Reduce power or deliver power in a more intelligent way (trackers at LHC need of order 100kW at less than 5V, current are huge, cables the same to keep losses acceptable). The services complicate the detector integration and compromises the performance.
- Reduce costs for silicon detectors (strip and various pixels). Today at PIXEL detector cost 5-10 MChf per m², strip trackers around 0.3-1 MChf per m². Similar arguments apply to large muon chambers.